## **SCOPE OF CLAIMS**

1. A method of forming one or more carbonaceous material projections, the method comprising the steps of:

applying a resist onto a carbonaceous material substrate;

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forming holes in the applied resist, the holes being provided according to a predetermined arrangement, each hole having a wall surface, and the wall surface being inversely tapered from an aperture thereof toward a bottom thereof;

depositing mask material for a mask on the carbonaceous material substrate to form a mask deposition in each hole;

lifting off the mask material deposited on the resist together with the resist; and

etching the carbonaceous material substrate by using the mask deposition as a mask to form one or more carbonaceous material projections.

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2. The forming method of the carbonaceous material projection according to claim 1, wherein the carbonaceous material projections have a projected diameter of not more than 300 nm, and a density of the carbonaceous material projections is equal to or more than 4 projections/ $\mu m^2$ .

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3. The forming method of the carbonaceous material projection according to claim 1 or 2, wherein each carbonaceous material projection is of a conical shape.

4. A method of forming a carbonaceous material projection, 25 the method comprising the steps of:

forming a film on a carbonaceous material substrate, the film

being made of one of a silicon-based nitride (SiN<sub>x</sub>: 0 < x < 1.33) and silicon-based nitride oxide (SiO<sub>x</sub>N<sub>y</sub>: 0 < x < 2, 0 < y < 1.3);

applying a resist onto the film formed on the carbonaceous material substrate, patterning the resist by one of photolithography and electron beam exposure to form a patterned resist of a dot shape, and processing the film by use of the patterned resist as a mask; and

etching the carbonaceous material substrate by use of an etching mask including the processed film to form a carbonaceous material projection.

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5. A carbonaceous material projection structure comprising a plurality of carbonaceous material projections provided according to a predetermined arrangement, a density of the carbonaceous material projections being not less than 4 projections/ $\mu$ m<sup>2</sup>, and tips of the projections being smaller than roots of the projections.

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6. A carbonaceous material projection structure comprising a plurality of carbonaceous material projections provided according to a predetermined arrangement, each carbonaceous material projection having an approximately conical shape, and an apex angle of each carbonaceous material projection being not more than 39 degrees.

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7. The carbonaceous material projection structure according to claim 6, wherein a tip diameter of each carbonaceous material projection is not more than 50 nm, and a uniformity of heights of the carbonaceous material projections is within  $\pm$  5%.

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8. The carbonaceous material projection structure according to claim 6 or 7, wherein a projection density of the carbonaceous material projections is not less than 4 projections/μm<sup>2</sup>.